



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/040,042 Confirmation No. 1835
Applicant : Wei-Yu Su
Filed : November 7, 2001
TC/A.U. : 1746
Title : Method for Reduction of Photomask Defects

Docket No. : N1085-90003
Customer No. : 08933

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

**CERTIFICATE OF MAILING,
37 C.F.R. §1.8(a)**

I certify that this correspondence and the enclosures mentioned therein are being deposited by First Class U.S. Mail with sufficient postage on the date shown below, addressed to Commissioner for Patents, PO Box 1450, Alexandria, Virginia 22313-1450.

Richard A. Paikoff
Richard A. Paikoff, Reg. No. 34,892
4/6/06
Date

AMENDMENT AND RESPONSE UNDER 37 CFR §1.116(a)

Sir:

In response to the Office Action of January 10, 2006, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.